








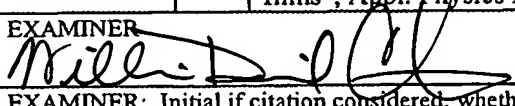
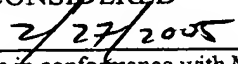


FORM PTO-1449 (SUBSTITUTE) U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE INFORMATION DISCLOSURE STATEMENT BY APPLICANT (37 CFR 1.98(b))				Attorney Docket No.: Divisional of Applic. No. GR 96 P 8091 D2 10/324,848 Applicant Michael Kelly et al. Filing Date of Divisional Group Art Unit September 29, 2003 2823			
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EXAMINER INITIALS	PATENT NO.	DATE	PATENTEE	CLASS	SUB CLASS	FILING DATE
	A	3,808,550	04/94	Ashkin		
	B	4,448,636	05/84	Baber		
	C	4,846,931	07/89	Gmitter et al.		
	D	4,883,561	11/89	Gmitter et al.		
	E	5,465,009	11/95	Drabik et al.		
	F	5,559,043	09/96	Bruehl		
	G	5,985,687	11/99	Bowers et al.		
	H	6,071,795	06/00	Cheung et al.		
	I	6,159,824	12/00	Henley et al.		




FOREIGN PATENT DOCUMENT							
DOCUMENT NO.	DATE	COUNTRY	CLASS	SUB CLASS	TRANSL. YES NO		
	J	DE 35 08 469 A1	09/86	Germany			
	K	EP 0 718 885 A2	06/96	Europe			
	L	EP 0 987 741 A1	03/00	Europe			
	M						
	N						

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)	
	M.K. Kelly et al.: "Optical Patterning of GaN films", Appl. Physics, Letter 69 (12), September 16, 1996, pp. 1749-51.
	Eli Yablonovitch et al.: "Extreme Selectivity in the Lift-Off of Epitaxial GaAs films", Appl. Physics Letter 51 (26), December 28, 1987, pp. 2222-24.
EXAMINER 	DATE CONSIDERED 
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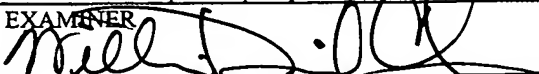
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OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)	
	R. Groh et al.: "On the Thermal Decomposition of GaN in Vacuum", pp. 353-57.
	Yasua Morimoto: "Few Characteristics of Epitaxial GaN-Etching and Thermal Decomposition", J. Electrochemical Society: Solid State Science and Technology, October 1974, pp. 1383-84.
EXAMINER 	DATE CONSIDERED 2/27/2005
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OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)	
	R.T. Leonard et al.: "Photoassisted Dry Etching of GaN", Appl. Physics , Letter 68, February 5, 1996, pp. 794-96.
	Young-Feng Lu et al.: "Laser-Induced Dry Lift-Off Process", Jpn. J. Appl. Physics, Volume 34, 1995, pp. 1669-70.
EXAMINER 	DATE CONSIDERED 2/27/2005


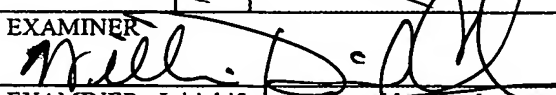
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	Young-Feng Lu et al.: "Excimer-Laser Removal of SiO ₂ Patterns from GaAs Substrates", Jpn. Appl. Physics, Volume 33, 1994, pp. 324-27.
	C.R. Miskys et al.: "MOCVD-Epitaxy on Free-Standing HVPE-GaN Substrates", Phys. Stat. Sol. (a) 176, 443 (1999), pp. 443-46.
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		L. Tsakalakos et al.: „Epitaxial Ferroelectric (Pb, La)(Zr, Ti)O ₃ Thin Films on Stainless Steel By Excimer Laser Liftoff“, Applied Physics Letters, Volume 76, No. 2, January 10, 2000, pp. 227-29.					
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